

PATENT Customer No. 22,852 Attorney Docket No. 04329.2959-01

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

in re Application of:	)
Gaku Minamihaba et al.	) Group Art Unit: 1765
Application No.: 10/762,514	.) Examiner: Chen, Eric Brice
Filed: January 23, 2004	) Confirmation No. 5239
For: SLURRY FOR CHEMICAL MECHANICAL POLISHING COPPER AND METHOD OF MANUFACTURING A SEMICONDUCTOR DEVICE USING THE SLURRY	)
Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450	
Sir:	

## **AMENDMENT**

In reply to the Office Action mailed March 21, 2006, with a period for response extending through June 21, 2006, please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper.

Remarks begin on page 4 of this paper.

Attachment to this Paper: Declaration Under 37 C.F.R. 1.132